Special Issue

Nanowire-Based Micro/Nano Devices

Message from the Guest Editors

Advances in nanomaterials and nanomanufacturing technologies have resulted in the development of technology platforms for micro/nanosensors related to various applications. In particular, devices based on one-dimensional nanostructures such as nanowires and nanorods have received considerable attention due to their excellent performance, high surface-to-volume ratio, and suitability for implementation in small-sized sensors and multifunctional sensor systems. This Special Issue will focus on the recent developments in nanowire-based device technology for sensor applications. Reviews and original research articles focusing on synthesis and growth, fabrication processes and technologies, nanomaterial properties, device integration concepts, and other relevant topics are welcome.

Keywords

- nanowires
- nanoparticles
- nano/microfabrication
- surface functionalization
- chemical sensors
- photoelectronic sensors
- sensor integration
- nanoelectrodes

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